

INFORMATION DISCLOSURE STATEMENT  
IN AN APPLICATION

February 1, 2005

(Use several sheets if necessary)

ATTORNEY DOCKET NO.  
3194.1026-006

APPLICATION NO.

**101523371**FIRST NAMED INVENTOR  
Jeffrey J. SpiegelmanFILING DATE  
6/21/05EXAMINER  
**Carrillo**CONFIRMATION NO.  
GROUP  
1792

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	REF. NO.	DOCUMENT NUMBER Number-Kind Code (if known)	ISSUE DATE / PUBLICATION DATE MM-DD-YYYY	NAME OF PATENTEE OR APPLICANT OF CITED DOCUMENT
/SC	AA	5,013,335	05-07-1991	Marcus
	AF	5,160,512	11-03-1992	Talu
	AC	5,230,721	07-27-1993	Ohmi
	AA	5,351,415	10-04-1994	Brooks <i>et al.</i>
	AF	5,540,757	07-30-1996	Jordan, Sr.
	AF	5,602,683	02-11-1997	Straaijer <i>et al.</i>
	AC	5,676,737	10-14-1997	Whitlock
	AA	5,883,738	10-14-1997	Carrea <i>et al.</i>
	AF	5,846,338	10-04-1998	Bonora <i>et al.</i>
	AJ	5,869,401	02-09-1999	Brunemeier <i>et al.</i>
	AA	5,902,643	10-19-1999	Roth
	AA2	5,968,232	10-19-1999	Whitlock
	AB2	6,124,211	09-26-2000	Butterbaugh <i>et al.</i>
	AG2	6,221,132 B1	04-24-2001	Dong <i>et al.</i>
	AD2	6,391,090 B1	05-21-2002	Alvarez, Jr. <i>et al.</i>
	AE2	6,427,703 B1	08-06-2002	Somekh
	AF2	6,461,410	10-08-2002	Abe <i>et al.</i>
V	AG2	6,638,341 B1	04-20-2004	Spiegelman <i>et al.</i>
/SC/	AH2	6,724,460 B2	04-20-2004	Van Schaik <i>et al.</i>

EXAMINER /Sharidan Carrillo/

DATE CONSIDERED 07/03/2007

PTO-1449 REPRODUCED

## **INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION**

February 1, 2005

(Use several sheets if necessary)

ATTORNEY DOCKET NO.  
3194-1026-006

**APPLICATION NO.**

**10/523371**

**FIRST NAMED INVENTOR**  
**Jeffrey J. Spiegelman**

FILING DATE  
6/21/05

**EXAMINER**

Carrillo

**CONFIRMATION N**

6/21/05

## **U.S. PUBLISHED APPLICATIONS**

**EXAMINER**

/Sharidan Carrillo/

**DATE CONSIDERED**

07/03/2007

INFORMATION DISCLOSURE STATEMENT  
IN AN APPLICATION

February 1, 2005

(Use several sheets if necessary)

FIRST NAMED INVENTOR  
Jeffrey J. SpiegelmanFILING DATE  
6/21/05EXAMINER  
CarrilloCONFIRMATION NO.  
GROUP  
1792

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER Country Code-Number-Kind Code (if known)	DATE MM-DD-YYYY	NAME OF PATENTEE OR APPLICANT OF CITED DOCUMENT	TRANSLATION YES      NO
/SC/ AL	WO 01/37329 A1	05-25-2001	Lucent Technologies, Inc.	
/SC/ AM	EP 0 867 924 A2	09-30-1998	Interuniversitair Micro-Elektronica Centrum VZW 3001 Heverlee (BE)	
/SC/ AN	DE 199 24 058 A1 (appended English Abstract Translation)	11-30-2000	Robert Bosch GmbH	
AO				
AT				
AO				
AL2				
AM2				
AN2				
AQ2				
AT2				
AQ2				
AL3				
AM3				
AN3				
AO3				
AP3				
AQ3				
AL4				
AQ4				

PTO-1449 REPRODUCED		ATTORNEY DOCKET NO. 3194.1026-006	APPLICATION NO. <b>10/523371</b>
INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION		FIRST NAMED INVENTOR Jeffrey J. Spiegelman	FILING DATE 6/21/05
February 1, 2005 (Use several sheets if necessary)		EXAMINER Carrillo	CONFIRMATION NO.
			GROUP 1752

OTHER DOCUMENTS (*Including Author, Title, Date, Pertinent Pages, Etc.*)

/SC/	AR	Handbook of Semiconductor Wafer Cleaning Technology, Science, Technology, and Applications, Werner Kern Associates, eds., (NJ: Noyes Publications) pp. 88-89 (1993).
/SC/	AS	Veillerot, Marc, "A Method for Measuring AMC Concentrations Inside Wafer Containers," Materials Integrity Management Symposium 2003.
/SC/	AT	Martin, Ray <i>et al.</i> , "Status of Microenvironment Gas Purge in the Semiconductor Industry," Materials Integrity Management Symposium 2003.
/SC/	AU	Davidson, John, "The Expanding Role of Bare Reticle Stockers in Photolithography," Materials Integrity Management Symposium 2003.
/SC/	AV	Veillerot <i>et al.</i> , "Organic Contamination: Purge Gas Impacts in Plastic Storage Boxes," Solid State Phenomena, vol. 92, pp. 105-108 (2003).
/SC/	AW	Veillerot <i>et al.</i> , "Testing the use of purge gas in wafer storage and transport containers," [online] 1997-2003 [retrieved 2004-11-10]. Retrieved from the Internet <URL: <a href="http://www.micromagazine.com/archive/03/08/verllerot.html">http://www.micromagazine.com/archive/03/08/verllerot.html</a>
/SC/	AX	Pearlstein <i>et al.</i> , "Evaluating electronics-grade gas-line purging requirements," [online] March, 2001 [retrieved 2004-10-18]. Retrieved from the Internet <URL: <a href="http://sst.pennnet.com/Articles/Article_Display.cfm?Section=ARCHI&amp;ARTICLE_ID=95491&amp;VERSION_NUM=1&amp;p=5">http://sst.pennnet.com/Articles/Article_Display.cfm?Section=ARCHI&amp;ARTICLE_ID=95491&amp;VERSION_NUM=1&amp;p=5</a>
	AY	
	AZ	
	AR2	
	AS2	
	AT2	

EXAMINER	/Sharidan Carrillo/	DATE CONSIDERED	07/03/2007
----------	---------------------	-----------------	------------